



Serial No. 09/851,089

SEC.837

Amendment dated 16 January 2004

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of:

Jong-Woon OH et al.

Group Art Unit: 1744

Serial No.: 09/851,089

Examiner: Laura C. COLLETT

Filed: 9 May 2001

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TC 1700

CLEANING APPARATUS FOR
SEMICONDUCTOR WAFER

**REQUEST TO WITHDRAW FINALITY OF OFFICE ACTION
AND
AMENDMENT UNDER 37 C.F.R. § 1.113 AND/OR 1.116**

U.S. Patent and Trademark Office
2011 South Clark Place
Customer Window, Mail Stop **AF**
Crystal Plaza Two, Lobby, Room 1B03
Arlington, VA 22202

Sir:

In response to the FINAL Office Action dated 24 October 2003, please amend the above-identified patent application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 5 of this paper.